

# Semiconductor Lasers

○ Homojunction semiconductor laser - 1962

Demonstrated by 4 research groups.

- R.N. Hall: GE Schenectady, NY.

- M.I. Nathan: IBM

- N. Holonyak: GE Syracuse

- Robert H. Rediker, Lincoln Lab

Heterojunction injection laser - 1963

Proposed by H. Kroemer 1963

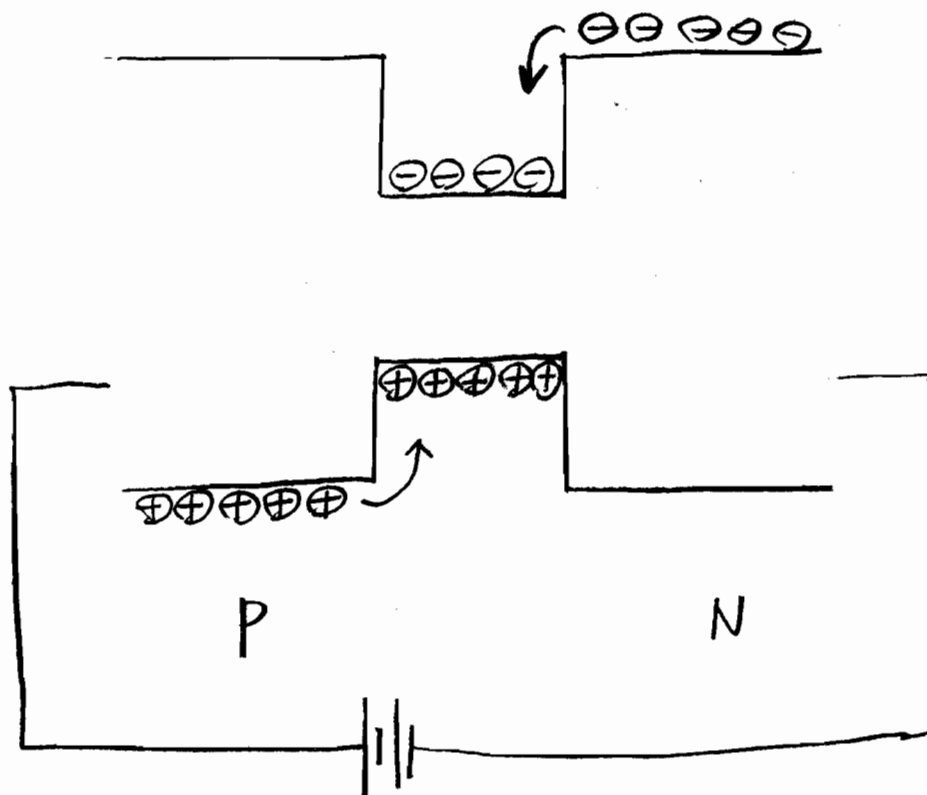
Double Heterostructure laser - 1970

Zh. I. Alferov

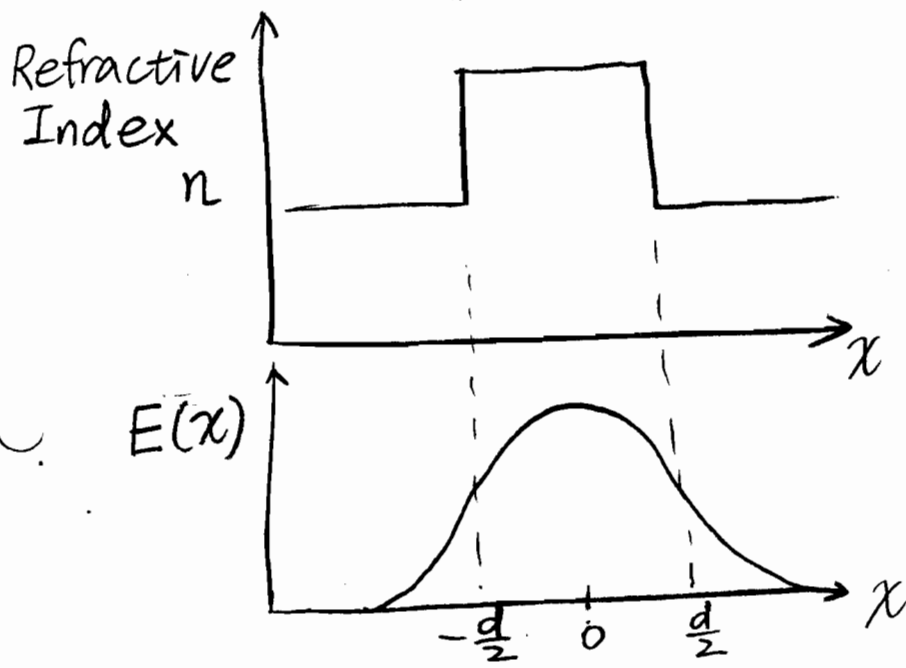
○ Quantum well lasers - late 1970's

Strained QW lasers - late 1980's

# Double Heterostructure (DH)



High concentration of both electrons and holes  
in the smaller-bandgap active region  
→ Carrier confinement



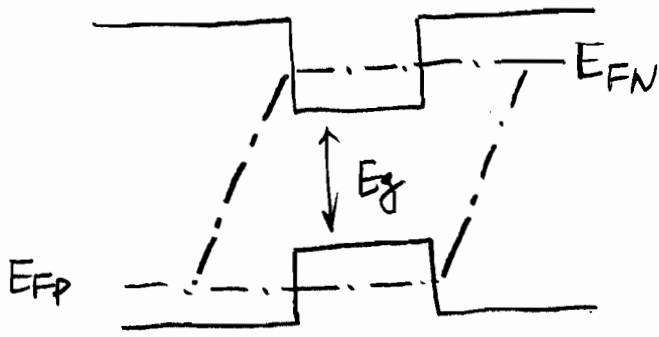
Small bandgap  
→ higher  $n$

⇒ Optical confinement

Confinement Factor

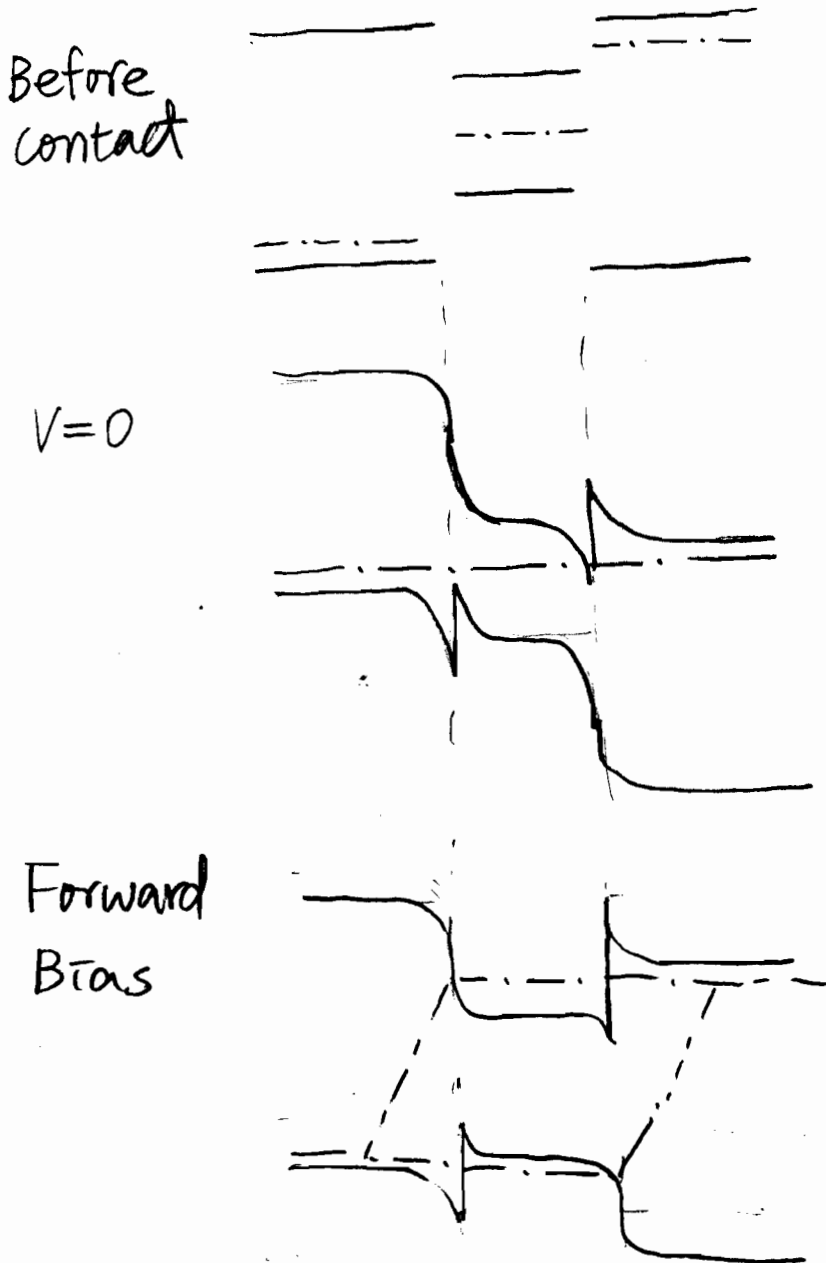
$$\Gamma = \frac{\int_{-d/2}^{d/2} |E(x)|^2 dx}{\int_{-\infty}^{\infty} |E(x)|^2 dx}$$

DH: Flat band



Condition for gain  
 $\Delta E_F > E_g$

Actual band diagram.



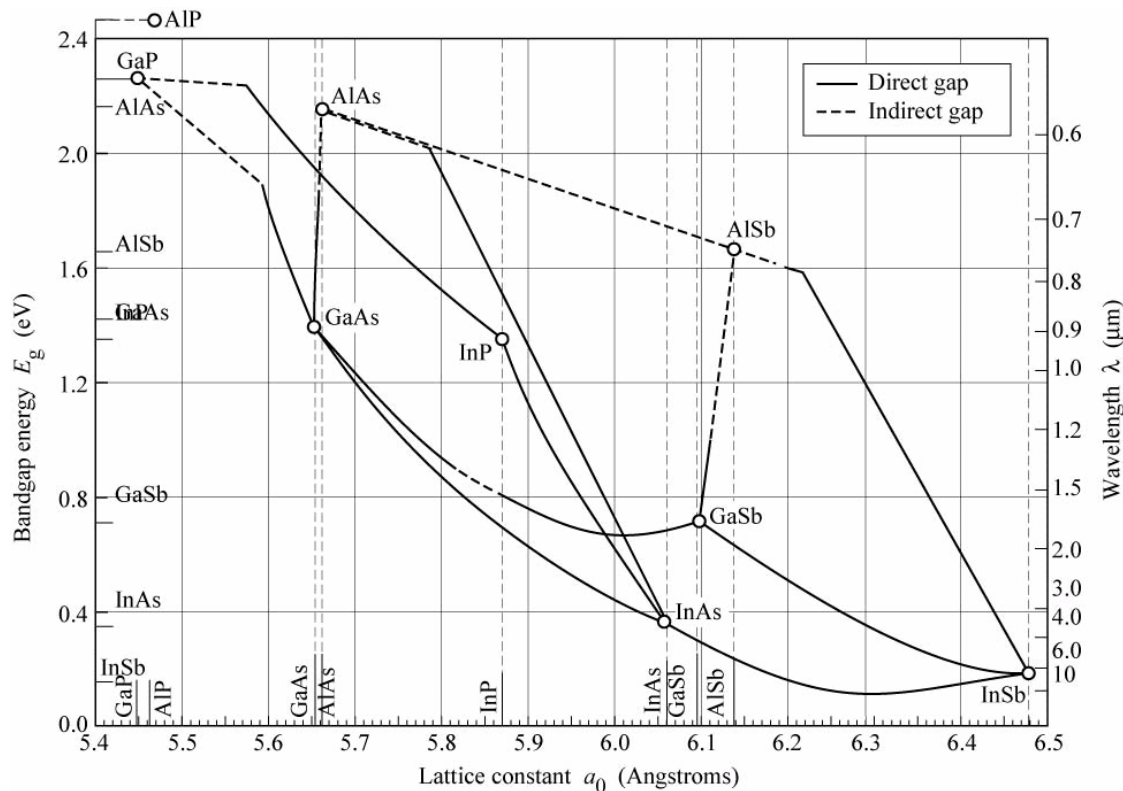


Fig. 12.6. Bandgap energy and lattice constant of various III-V semiconductors at room temperature (adopted from Tien, 1988).

E. F. Schubert  
 Light-Emitting Diodes (Cambridge Univ. Press)  
[www.LightEmittingDiodes.org](http://www.LightEmittingDiodes.org)

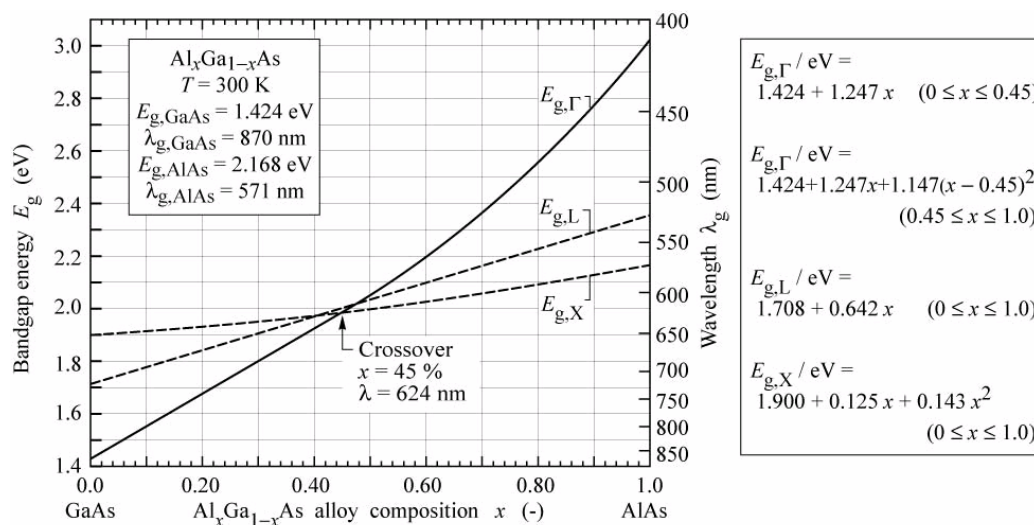
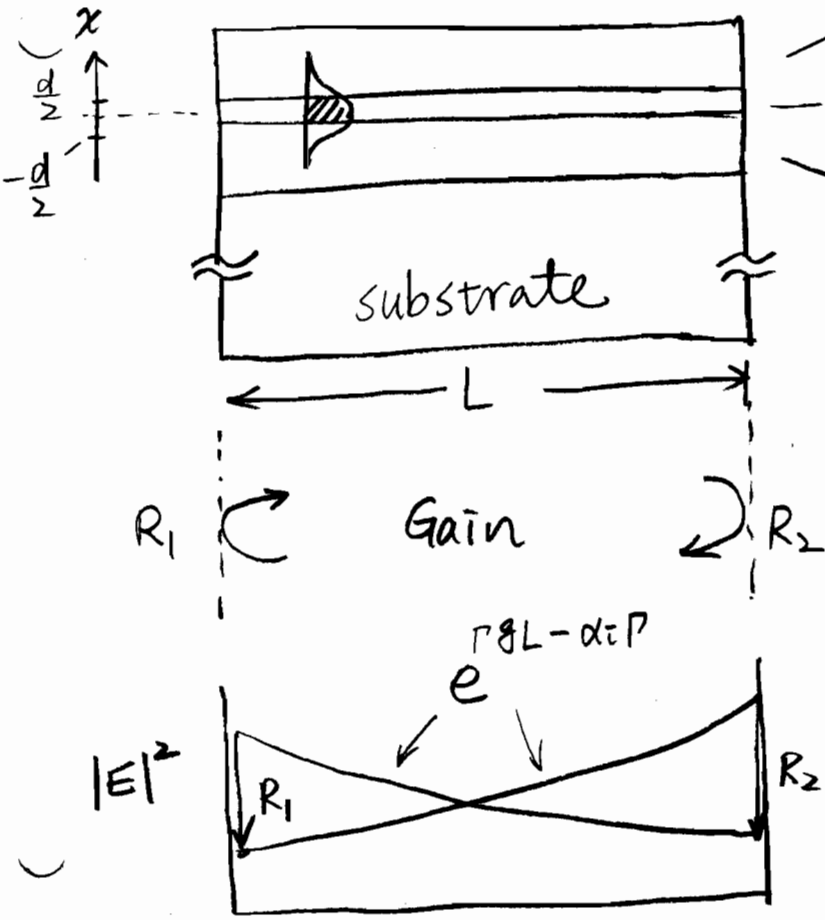


Fig. 12.7. Bandgap energy and emission wavelength of AlGaAs at room temperature.  $E_{\Gamma}$  denotes the direct gap at the  $\Gamma$  point and  $E_L$  and  $E_X$  denote the indirect gap at the L and X point of the Brillouin zone, respectively (adopted from Casey and Panish, 1978).

# DH Laser



Upper cladding  
Active  
Lower cladding

Uncoated facet

$$r = \frac{n-1}{n+1} \approx 0.56, \quad n \approx 3.5$$

$$R = r^2 = \left(\frac{n-1}{n+1}\right)^2 \approx 31\%$$

Material gain =  $g$

Modal gain =  $\Gamma g$

Confinement factor =  $\Gamma$

$$\Gamma = \frac{\int_{-d/2}^{d/2} |E(x)|^2 dx}{\int_{-\infty}^{\infty} |E(x)|^2 dx}$$

## Threshold Condition

$$e^{(\Gamma g_{th} - \alpha_i)L} \cdot R_2 \cdot e^{(\Gamma g_{th} - \alpha_i)L} \cdot R_1 = 1$$

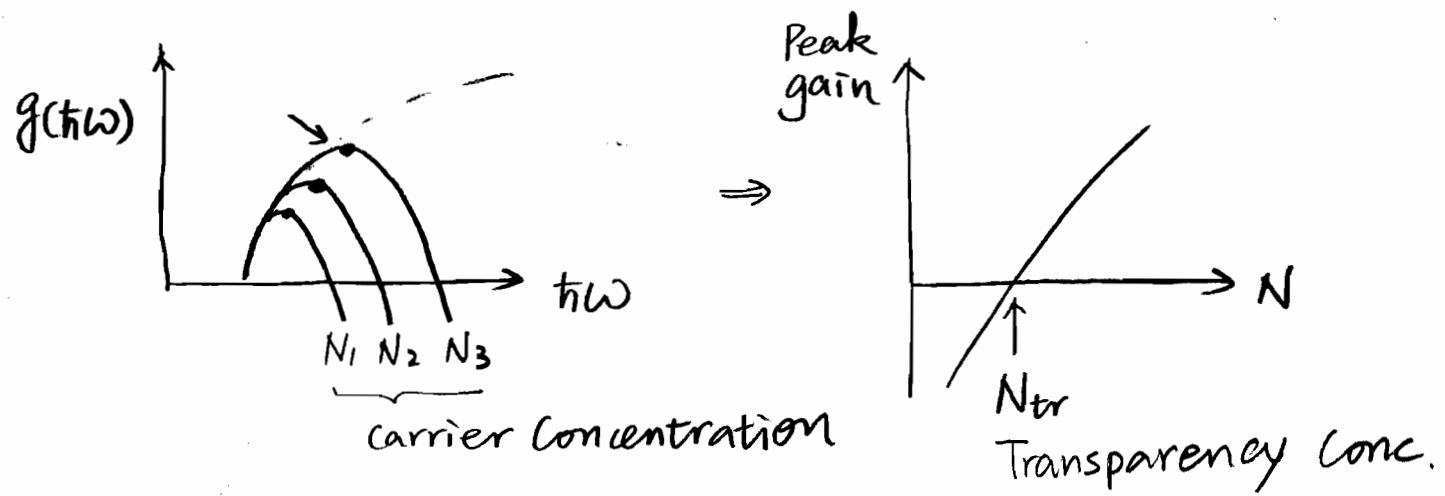
$$R_1 R_2 e^{2(\Gamma g_{th} - \alpha_i)L} = 1$$

$$\Gamma g_{th} - \alpha_i = \frac{1}{2L} \cdot \ln \frac{1}{R_1 R_2} \equiv \alpha_m = \text{distributed mirror loss (cm}^{-1}\text{)}$$

$$g_{th} = \frac{1}{\Gamma} (\alpha_i + \alpha_m)$$

↑ real loss      ↑ useful loss (output power)

# Linear Gain Approximation.



$$g(N) = a(N - N_{tr})$$

$$g_{th} = g(N_{th}) = a(N_{th} - N_{tr}) = \frac{1}{\Gamma} (\alpha_i + \alpha_m)$$

$$N_{th} = N_{tr} + \frac{1}{\Gamma a} (\alpha_i + \alpha_m)$$

Threshold current density  $J_{th}$

$$J_{th} = \frac{N_{th}}{\tau_e} \cdot \beta \cdot d$$

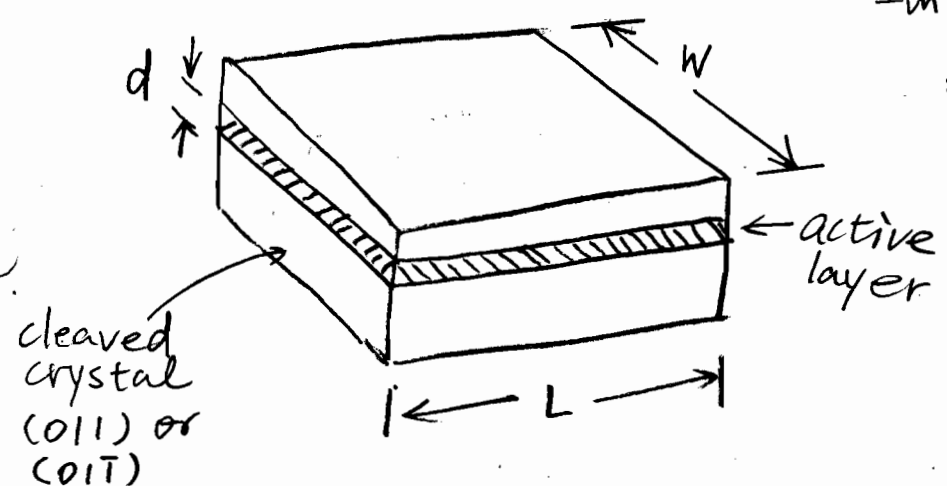
active layer thickness

$\tau_e$  = carrier lifetime

$$I_{th} = J_{th} \cdot W \cdot L$$

$$= \frac{N_{th}}{\tau_e} \cdot \beta \cdot (d \cdot W \cdot L)$$

active volume



$\tau_e$  is usually a function of  $N$  also

$$\frac{N}{\tau_e(N)} = R(N) = A_{nr}N + BN^2 + CN^3$$

↑

Recombination  
Rate

$A_{nr}N$  : Nonradiative recombination

$BN^2$  : Spontaneous recomb.

$CN^3$  = Auger Recomb.

(collision of 2 electrons,  
knocking 1 electron to VB  
and the other to higher  
energy CB)

